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Substitute for form 1449/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet 1

of 3

Complete if Known

Application Number	Not Yet Assigned	10/730,533
Filing Date	12/08/2003	
First Named Inventor	Chung-Hsing Chang	
Art Unit	Not Yet Assigned	1756
Examiner Name	Not Yet Assigned	Ruggles
Attorney Docket Number	N1085-00018	

U. S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

¹EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.² Applicant's unique citation designation number (optional).³ See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04.⁴ Enter the Office that issued the document, by the two-letter code (WIPO Standard ST.3).⁵ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.⁶ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible.⁷ Applicant is to place a check mark here if English language Translation is attached.

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Sheet	2	of	3	Attorney Docket Number	N1085-00018

NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			T ²
JSR	A	JOHN S. PETERSEN ET AL., "Development Of A Sub-100nm Integrated Imaging System Using Chromeless Phase-Shifting Imaging With Very High NA KrF Exposure And Off-Axis Illumination." 14 pages.			
	B	FUNG CHEN ET AL., "Binary Halftone Chromeless PSM Technology For Lambda/4 Optical Lithography," Optical Microlithography XIV, Proceedings of SPIE Vol. 4346 /2001 Pages 515 - 533			
	C	KATHERINE DERBYSHIRE, "Next-Generation Lithography: Beyond 100 NM, In The NGL Race, Only Extreme Ultraviolet And Projection Beam Technologies Are Still Contenders" at			
		http://www.semi.org/web/wrmagazine.nsf/4f55b97743c2d02e882565bf006c245... 10/11/2003, 8 pages			
	D	DOUGLAS VAN DEN BROEK, "Transferring Phase-Shifting Mask Technology Into Mainstream Manufacturing," at http://www.semiconductorfabtech.com/features/lithography/articles/body5.225... 10/11/2002, 8 pages			
	E	IBM, LARS W. LIEBMANN, "Layout Impact Of Resolution Enhancement Techniques: Impediment Or Opportunity?", Pages 110-117			
	F	LONG QUE ET AL., "Chromeless Phase-Shift Technology: The Physical Mechanism Of The Dark Area Produced by Phase-Compensation And Its Application," SPIE Vol. 1927			
JSR		Optical/Laser Microlithography VI (1993), Pages 709 - 714.			

Examiner Signature	<i>John Ruggles</i>	Date Considered	<i>3/8/06</i>
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Examiner Signature	<i>John Ruggles</i>	Date Considered	3/8/06
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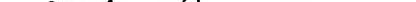
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